



MEMS-based Actuators

Guest Editor:

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Message from the Guest Editor

In this Special Issue, a wide range of topics are covered, including the design, fabrication, characterization, packaging and system integration or final applications of Micro/Nano-Electro-Mechanical Systems (MEMS/NEMS)-based actuators:

- Material research oriented to actuator microsystems and functional thin film materials
- Processes and fabrication technologies for miniaturized actuator systems
- Modelling and simulation of actuator microsystems
- Electrostatic, piezoelectric, mechanical, thermal, acoustic, magnetic or any physical actuation principles
- Optical MEMS (MOEMS), optoelectronic actuators
- Chemical and bio-actuators
- Calibration, characterization and testing techniques for MEMS-based actuators
- Reliability and failure analysis
- System integration, interface electronics, micromechatronics and microrobotics
- Applications and markets, control and measurement systems based on miniaturized/microactuators

